

Kwang Young Lee

Changsik Kim, Zheng Yang and Won Jong Yoo

SKKU Advanced Institute of Nano-Technology (SAINT), Sungkyunkwan University, 2066, Seobu-ro, Jangan-gu, Suwon, Gyeonggi-do 16419, Korea

[Contact@E-mail \(Arial Narrow 12\)](#)

Fermi level de-pinning induced by metallic edge-contact to TMDC

Future semiconductor technology can be realized by employing atomically thin two-dimensional (2D) structures, eg. transition metal dichalcogenides (TMDCs). Fermi-level pinning occurs when a metal is in contact with a semiconductor. In most cases, semiconducting characteristics of TMDC are expected to be ambipolar, but that of MoS₂ showed strong n-type behavior. To achieve p-type behavior from MoS₂ semiconductor devices, de-pinning of the contact metal is required, since pinning is very strong in them. In this work, we demonstrate that, when the high work function of palladium (Pd) is used to form edge contact on multi-layer MoS₂, p-type behavior is realized. In contrast, multi-layer MoS₂ device fabricated with edge-contact of low work function chromium (Cr) did not show p-type behavior. Furthermore, to understand interfacial properties of another 2D material, we employed the same metals (Cr & Pd) on multi-layer MoTe₂ devices. The surface-contact samples of MoTe₂ using these metals showed only ambipolar behaviour, and no changes in electrical results were observed despite the use of different work function metals. However, when edge-contact made with low work function metal Cr showed n-type behavior, while edge-contact with high work function Pd showed p-type due to de-pinning of Fermi level at the MoTe₂ and metal interface. This opens up a new area of study to designs polarity control of 2D TMDC materials based electronic devices.

Acknowledgments

This work was supported by the Global Research Laboratory (GRL) Program (2016K1A1A2912707) and Global Frontier R&D Program (2013M3A6B1078873), both funded by the Ministry of Science, ICT & Future Planning via the National Research Foundation of Korea (NRF).